

Qty	Description
1	<p data-bbox="260 215 587 241">System, Inspection, NSX320</p> <p data-bbox="260 275 523 302">General Specifications:</p> <ul data-bbox="260 304 1027 739" style="list-style-type: none"> <li data-bbox="260 304 916 331">• Monochrome inspection camera - up to 85 frames/second</li> <li data-bbox="260 333 512 360">• Color review camera</li> <li data-bbox="260 362 967 389">• Defect sensitivity to 0.5 microns (applications study required)</li> <li data-bbox="260 392 983 450">• Illumination: high-speed strobe for brightfield and darkfield ring light</li> <li data-bbox="260 452 1027 479">• Laser point sensor for high-speed mapping of wafer surface profile</li> <li data-bbox="260 481 831 508">• Linear staging using continuous scan technology</li> <li data-bbox="260 510 544 537">• Vibration isolated stage</li> <li data-bbox="260 539 707 566">• Clean room ISO class 100 compatible</li> <li data-bbox="260 568 874 595">• Sawn wafers up to 300mm on film frames and hoops</li> <li data-bbox="260 598 1019 656">• Capable of inspection multiple substrates when equipped with the necessary automation handler</li> <li data-bbox="260 658 695 685">• Windows XP 64 bit operating system</li> <li data-bbox="260 687 719 714">• Automatic data collecting and reporting</li> <li data-bbox="260 716 467 743">• Clean Air Ionizer</li> </ul> <p data-bbox="260 772 456 799">System Includes:</p> <ul data-bbox="260 801 1027 1120" style="list-style-type: none"> <li data-bbox="260 801 496 828">• Inspection Platform</li> <li data-bbox="260 831 1027 889">• Choice of inspection platforms with hard-anodized finish which can accommodate 100mm to 300mm whole wafers.</li> <li data-bbox="260 891 1027 1003">• Turret Assembly, Standard - The objective turret provides flexibility for inspection applications requiring both high throughput and high resolution. The turret assembly includes any 3 of the following 1X, 2X, 3X, 5X, 10X and 20X objectives.</li> <li data-bbox="260 1005 1011 1064">• 2D Defect &amp; Metrology Verification, Standard - Designed to verify system functionality and repeatability</li> <li data-bbox="260 1066 568 1093">• Programmable light tower</li> <li data-bbox="260 1095 568 1122">• Standard docking module</li> </ul>

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1	<p data-bbox="260 1205 638 1232">System, XPort, System &amp; X-Tool</p> <p data-bbox="260 1261 488 1288">XPort Base System</p> <p data-bbox="260 1319 1027 1404">The XPort is an ISO class 1 clean high speed wafer handling EFEM outfitted with a dual arm robot designed for minimal wafer swap times. The XPort is designed to accommodate:</p> <ol data-bbox="260 1435 999 1494" style="list-style-type: none"> <li data-bbox="260 1435 999 1494">1. Two (2) 300 mm Brooks Load Ports - Vision loadports and two OCA boxes.</li> </ol> <p data-bbox="260 1525 952 1583">The XPort is capable of handling standard wafer thicknesses (725um) down to 400 micron thickness for 300mm wafers</p> <p data-bbox="260 1615 952 1673">The XPort is capable of handling standard wafer thicknesses (725um) down to 190 micron thickness for 200mm wafers</p> <p data-bbox="260 1704 716 1731">Note: Must select loadport configuration</p> <p data-bbox="260 1785 485 1812">Standard Features:</p> <ul data-bbox="260 1843 935 2045" style="list-style-type: none"> <li data-bbox="260 1843 659 1870">o Automated whole wafer handling</li> <li data-bbox="260 1901 844 1928">o Dual Arm vacuum assist backside wafer handling</li> <li data-bbox="260 1960 608 1986">o Minimal contact end effector</li> <li data-bbox="260 2018 935 2045">o Integrated laminar clean air flow mini-environment (ULPA</li> </ul>

Filtration)

- o Robot with integrated mapper
- o Standard five (5) Color Light Tower